

Effect of Low-Temperature TFT Processing on Power Delivery from Thin-Film Power Electronics on Flexible Substrates

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Abstract

We have recently shown thin-film systems combining energy-harvesting devices possible in large-area electronics with embedded power electronics based on thin-film transistors (TFTs), creating complete powering systems. Power inverters are built to perform DC to AC conversion from large thin-film solar cells, enabling substantial wireless power delivery to mobile load devices or to other physical “planes” (layers) in a large-scale thin-film system. To realize non-rigid planes, we use low-temperature amorphous-silicon (a-Si) processing for TFTs in the power circuits [1]. We previously illustrated how TFT characteristics (e.g. f_t) impact performance of these systems; in this paper we show how provision of output power is affected by stability of TFTs in the thin-film circuits and how degradation can be mitigated.

Results are presented for a TFT LC-oscillator-based inverter [1,2], drawing DC power from an a-Si solar module ($V_{op} \approx 35V$) and transmitting this through near-field inductive coupling to load devices. The oscillator is two cross-coupled, SiNx-passivated, back-channel-etched TFTs ($W/L=3600/6\mu m$) with planar Cu inductors ($10cm^2$, $L=150\mu H$, $R=35\Omega$) forming tanks at TFT drains; the inductors resonate with the TFT capacitances ($C_t \approx 30pF$) enabling wireless power transfer ($>20mW$). We fabricate our inverters on free-standing $50\mu m$ polyimide at process temperatures $<180C$.

We show that output power decrease over time results from TFT instability, caused by threshold-voltage shift. For $V_{op} < 35V$ and a SiNx TFT dielectric, this is from moderate gate field (on average $<10^6 V/cm$) V_t shift [3] of oscillator TFTs of the form $t^\alpha \beta$ with $\beta=0.40$ (previously associated with defect creation at the a-Si-dielectric interface). The oscillator stress conditions are complex, as large AC swings at TFT drain/gate nodes result in devices moving between linear/saturation regimes, with biasing voltages oscillating about a non-zero average, V_{op} . DC stressing in 3 regimes ($V_{ds} > V_{gs}$, $V_{ds} < V_{gs}$ and $V_{ds} = V_{gs}$) suggests V_t shift mainly occurs while TFTs are in saturation. After 3 hours, average oscillator current drops by 25% resulting in 17% decrease in power delivery from reduced TFT gm, lowering oscillator voltage swing.

This gm reduction also affects the oscillator's required positive feedback condition, $(g_m/C_t) \times (L/R) > 1$ [2]. We show that large L/R ratio inductors, achievable by large-area patterning, make the power-inverter less sensitive to long-term TFT drift. Raising gate nitride deposition temperature can improve the dielectric-channel interface, reduce V_t shift [3] and maintain gm. At higher temperatures, however, larger misalignments result between device layers, requiring larger source/drain overlaps to maintain successful operation (hence larger C_t). We show experimental data for this tradeoff, noting that larger C_t affects the positive feedback condition, output power and power-transfer efficiency.

1. Rieutort-Louis et al. IEDM 2012
2. Hu et al. CICC 2012
3. Kattamis et al. EDL 2007